L Number	Hits	Search Text	DB	Time stamp
1	89553	non-volatile or nonvolatile near5 memor$3	USPAT; US-PGPUB; JPO	2003/06/10 10:21
2	18309	float$3 near3 gate$1	USPAT; US-PGPUB; JPO	2003/06/10 10:22
3	56191	control near2 gate$1	USPAT; US-PGPUB; JPO	2003/06/10 10:22
4	25443	select$3 near2 gate$1	USPAT; US-PGPUB; JPO	2003/06/10 10:22
5	95088	polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon))	USPAT; US-PGPUB; JPO	2003/06/10 10:23
6	4383	(non-volatile or nonvolatile near5 memor$3) and (float$3 near3 gate$1) and (control near2 gate$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))	USPAT; US-PGPUB; JPO	2003/06/10 10:23
7	1754026	source$1 or drain$1	USPAT; US-PGPUB; JPO	2003/06/10 10:23
8	4175	((non-volatile or nonvolatile near5 memor$3) and (float$3 near3 gate$1) and (control near2 gate$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source$1 or drain$1)	USPAT; US-PGPUB; JPO	2003/06/10 10:24
9	301054	etch$3	USPAT; US-PGPUB; JPO	2003/06/10 10:24
10	132929	implant$3	USPAT; US-PGPUB; JPO	2003/06/10 10:24
11	1948	(((non-volatile or nonvolatile near5 memor$3) and (float$3 near3 gate$1) and (control near2 gate$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source$1 or drain$1)) and etch$3 and implant$3	USPAT; US-PGPUB; JPO	2003/06/10 10:24
12	750	((((non-volatile or nonvolatile near5 memor$3) and (float$3 near3 gate$1) and (control near2 gate$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source$1 or drain$1)) and etch$3 and implant$3) and (select$3 near2 gate$1)	USPAT; US-PGPUB; JPO	2003/06/10 10:26
27	3543	eras$3 near2 gate$1	USPAT; US-PGPUB; JPO	2003/06/10 12:16
28	161024	polish$3 or cmp	USPAT; US-PGPUB; JPO	2003/06/10 12:17
29	750	((((non-volatile or nonvolatile near5 memor$3) and (float$3 near3 gate$1) and (control near2 gate$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source$1 or drain$1)) and etch$3 and implant$3) and (select$3 near2 gate$1)	USPAT; US-PGPUB; JPO	2003/06/10 12:17
30	634	((((non-volatile or nonvolatile near5 memor$3) and (float$3 near3 gate$1) and (control near2 gate$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source$1 or drain$1)) and etch$3 and implant$3) and (eras$3 near2 gate$1)	USPAT; US-PGPUB; JPO	2003/06/10 12:17
31	309	(((((non-volatile or nonvolatile near5 memor$3) and (float$3 near3 gate$1) and (control near2 gate$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source$1 or drain$1)) and etch$3 and implant$3) and (eras$3 near2 gate$1)) not (((((non-volatile or nonvolatile near5 memor$3) and (float$3 near3 gate$1) and (control near2 gate$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source$1 or drain$1)) and etch$3 and implant$3) and (select$3 near2 gate$1))	USPAT; US-PGPUB; JPO	2003/06/10 12:17

C:\APPS\east\workspaces\---ACOLLECTIONSEARCH-06.wsp

| 32 | | 61 | (polish\$3 or cmp) and (((((((non-volatile or nonvolatile near5 memor\$3) and (float\$3 near3 gate\$1) and (control near2 gate\$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source\$1 or drain\$1)) and etch\$3 and implant\$3) and (eras\$3 near2 gate\$1)) not (((((non-volatile or nonvolatile near5 memor\$3) and (float\$3 near3 gate\$1) and (control near2 gate\$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source\$1 or drain\$1)) and etch\$3 and implant\$3) and (select\$3 near2 gate\$1))) | USPAT; US-PGPUB; JPO | 2003/06/10 12:17 |
| 33 | | 248 | ((((((non-volatile or nonvolatile near5 memor\$3) and (float\$3 near3 gate\$1) and (control near2 gate\$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source\$1 or drain\$1)) and etch\$3 and implant\$3) and (eras\$3 near2 gate\$1)) not (((((non-volatile or nonvolatile near5 memor\$3) and (float\$3 near3 gate\$1) and (control near2 gate\$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source\$1 or drain\$1)) and etch\$3 and implant\$3) and (select\$3 near2 gate\$1))) not ((polish\$3 or cmp) and (((((((non-volatile or nonvolatile near5 memor\$3) and (float\$3 near3 gate\$1) and (control near2 gate\$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source\$1 or drain\$1)) and etch\$3 and implant\$3) and (eras\$3 near2 gate\$1)) not (((((non-volatile or nonvolatile near5 memor\$3) and (float\$3 near3 gate\$1) and (control near2 gate\$1) and (polysilicon or polysi or poly-si or (polycrystalline adj (si or silicon)))) and (source\$1 or drain\$1)) and etch\$3 and implant\$3) and (select\$3 near2 gate\$1)))) | USPAT; US-PGPUB; JPO | 2003/06/10 12:22 |

C:\APPS\east\workspaces\---ACOLLECTIONSEARCH-06.wsp